

HTTACK #5					
SHEET 1 OF 1					

ENFORMATION DISCLOSURE CITATION IN AN APPLICATION			57810-031 SERIAL NO.				L U.S. PT			
				APPLICANT Tatsuya KUNISATO, et al.					jc971 10∥⁄	
(PTO-1449)				FILING DATE GROUP February 25, 2002				-		
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